

**MicroPyros** LAAS

## Miniaturisation of Solid Propellant Thrusters for Space Application

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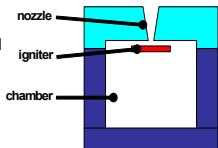
## Outline

- Introduction – MicroPyros project
- MicroPyros demonstrator
  - Millimeter-scale DEMO
- Microscale device
  - Design, fabrication, assembling
  - Characterisation
- Conclusion & outlook

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## Introduction

- MicroPyros project objectives (2000-2003)
  - Integration of energetic material, MEMS device and electronics to realise new performing PowerMEMS
  - Application of MicroPyrosystems to propulsion
    - Nanosatellite: micropropulsion for station keeping
- Solid propellant concept
  - Combustion of a solid material stored in a micromachined chamber



nozzle  
 igniter  
 chamber

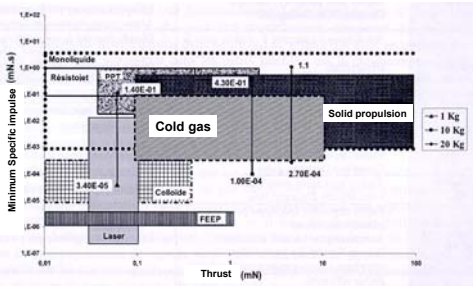
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## Introduction

- Solid propellant technology
  - Combustion : large quantity of energy from small volume
  - Solid fuel : no leakage, stability in time
  - No moving parts, eliminating frictional force and making technological fabrication easier
  - The chamber is not pressurised, the reservoir does not need to be massive

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## Introduction

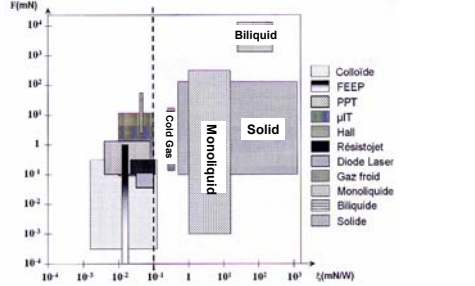


Minimum Specific Impulse (mN.s) vs Thrust (mN)

From B. Larangot, Conception, fabrication, caractérisation de matrices de micropropulseurs pyrotechniques sur silicium, Thesis, LAAS/CNRS, 2004

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## Microthrusters : mm-scale DEMO

- Single shot microthruster
  - ▶ Array of 4 x 4 microthrusters (16 thrusters)

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## Challenges

- Compromises between the reduction of the dimensional features and combustion process considerations
- Management in a very small volume of high temperature and pressure that could lead to mechanical failure
- Limits of silicon and the introduction of best appropriate materials implying to bond different materials together
- Compatibility of processing and assembling with the propellant

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## DEMO Design

- Array of 4 x 4 microthrusters
- Chip size : 14.65 mm x 14.65 mm

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## DEMO Fabrication Technology

	Material	Technology
<b>Nozzle (IMT)</b>	Si	Diverging angle : conic DRIE Cavity : KOH
<b>Igniter (LAAS)</b>	Si, polySi	RIE, DRIE
<b>Chamber (IMT)</b>	Si	DRIE
	Foturan	HF10%

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## DEMO Assembling

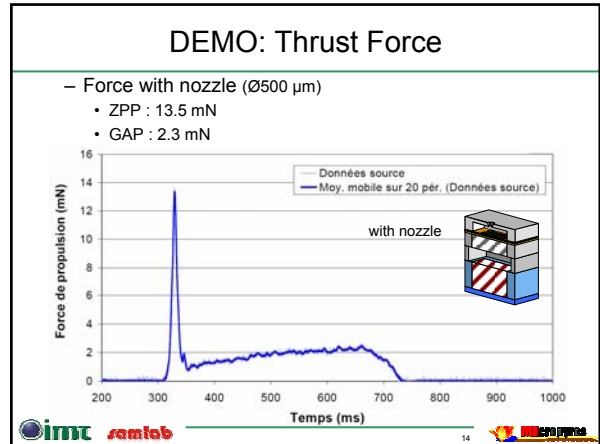
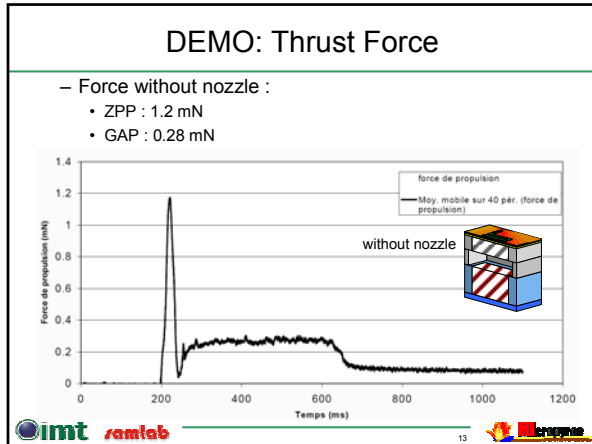
- Filling of the parts with propellant
  - Igniter
  - Sealed chamber
- Assembling
  - Anodic bonding
  - Thermal gluing (epoxy glue)

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## DEMO: Tests

- Set-up
  - Source I, measure V(t) => power, energy calculated
  - Thrust balance : thrust force measurement (LAAS)
- Ignition tests (GAP / GAP)
  - Ignition power : 100–150 mW
  - Ignition time : 20–130 ms
  - Combustion time : ~ 320 ms
- Ignition tests (ZPP / GAP)
  - Ignition power 150–200 mW
  - Ignition time : 80–130 ms
  - Combustion time : ~ 270 ms

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### Microscale Device

- Objective
  - Investigation of the limit of integration
  - Miniaturisation
  - Reduction of the number of parts
- Microthruster dimensions
  - MicroPyros DEMO (macro-scale device)
    - $\rightarrow 1500 \mu\text{m} \times 1500 \mu\text{m}$
  - Microscale device
    - $\rightarrow 1040 \mu\text{m} \times 1040 \mu\text{m}$  and  $500 \mu\text{m} \times 500 \mu\text{m}$  ( $275 \mu\text{m} \times 275 \mu\text{m}$ )

### Microscale Device Design

- Igniter on membrane (Design 1)
  - Same design than MicroPyros with smaller dimensions
- « Free standing » igniter (Design 2)
  - New design

### Igniters

- Heaters characteristics:

Area	1 mm	500 $\mu\text{m}$
180 x 180 $\mu\text{m}^2$	1020 $\Omega$	830 $\Omega$
390 x 390 $\mu\text{m}^2$	1975 $\Omega$	1730 $\Omega$
720 x 720 $\mu\text{m}^2$	3340 $\Omega$	—

### Nozzles

- Throat diameters

Diameter	1 mm	500 $\mu\text{m}$
275 $\mu\text{m}$	—	X
375 $\mu\text{m}$	X	X
500 $\mu\text{m}$	X	—

- Silicon bulk micromachining: DRIE and KOH

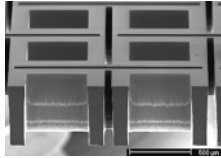

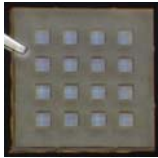
## Chamber Fabrication




- Technology developed for the mm scale design
  - DRIE of silicon wafers
  - Wet etching of Foturan glass wafers

Si: 500  $\mu\text{m}$  chambers  
50  $\mu\text{m}$  grooves

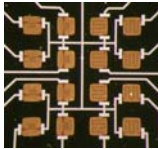
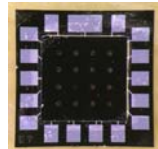
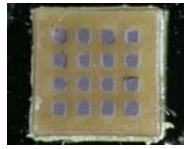
Si: 500  $\mu\text{m}$  chambers  
250  $\mu\text{m}$  grooves


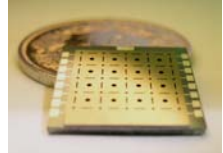
Foturan: 500  $\mu\text{m}$  chambers










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## Assembling

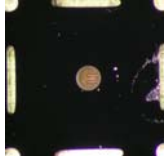
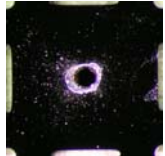








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## Ignition and Combustion

- Constant current of 7.0 to 7.75 mA


Area	1 mm	500 $\mu\text{m}$
180 x 180 $\mu\text{m}^2$	60-90 mW	65 to 105 mW
390 x 390 $\mu\text{m}^2$	130-200 mW	125-200 mW
720 x 720 $\mu\text{m}^2$	200-375 mW	–









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## Ignition and Combustion

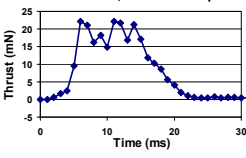
- Ignition time: 27 to 37 ms
- Ignition energy: 4.9 to 7.9 mJ



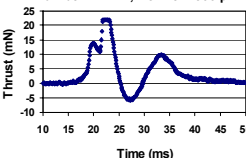


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## Ignition and Combustion

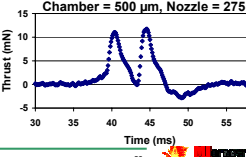
Chamber = 1mm, Nozzle = 500  $\mu\text{m}$






Chamber = 1mm, Nozzle = 500  $\mu\text{m}$



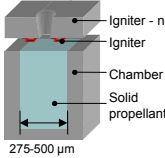
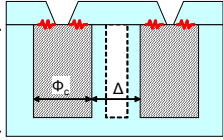
Chamber = 500  $\mu\text{m}$ , Nozzle = 275  $\mu\text{m}$



- Combustion time: 10 to 15 ms
- Thrust force: 12 to 23 mN






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## Microscale Device: Compact design

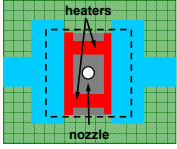
$\Phi_c$ [ $\mu\text{m}$ ]	$\Delta$ [ $\mu\text{m}$ ]	groove [ $\mu\text{m}$ ]	nozzle diameter [ $\mu\text{m}$ ]
500	250	50	180- 240
500	500	200	
275	225	50	100 - 130
	475	175	

– Array of 4 x 4 microthrusters, chip dimension of 8 x 8 mm<sup>2</sup>



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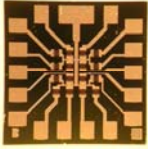
## SOI Igniters Fabrication


- SOI igniters



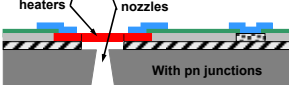
heaters  
nozzle

- SOI
- Si doping
- Si DRIE
- LPCVD Si<sub>3</sub>N<sub>4</sub>
- conic DRIE
- release : HF 50%
- Al contacts

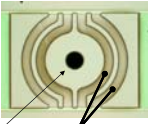




Without pn junctions



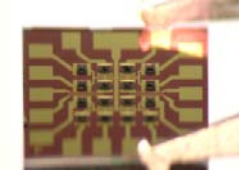
With pn junctions

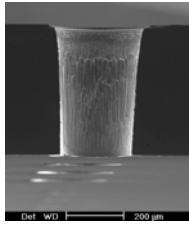


Nozzle  
Si suspended resistors


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## SOI Igniters





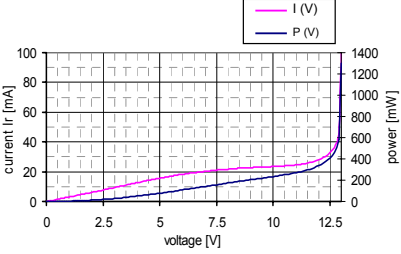
Def WD 500 µm




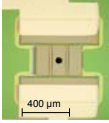
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## SOI Igniter Characterisation

– Maximum electrical power controlled by a limitation on the current delivered



Voltage [V]	Current Ir [mA]	Power [mW]
0	0	0
2.5	~10	~25
5	~20	~100
7.5	~30	~225
10	~40	~400
12.5	~50	~625

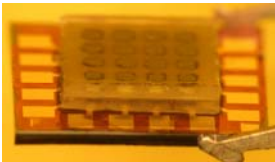
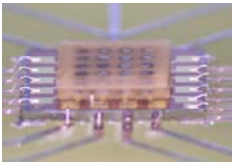



400 µm

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## Assembled SOI Thrusters

- One step filling procedure
- One bonding step (epoxy gluing)


- Heater: 200 to 400 ohms  
2 x 1 or 2 x 2 beams

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## Ignition SOI Thrusters

Constant Current of 10 to 24 mA / beam

- Ignition time: 6 to 24 ms
- Ignition power: 225 to 400 mW
- Ignition energy: 1.6 to 11.8 mJ



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## Conclusion

- Micrometer scale device
  - Design and specification of a micrometer scale device
  - Processing development to fabricate smaller igniters with integrated nozzles
  - Successful ignition of ZPP stored in sub-mm cavities
- Key points:
  - reproducibility of the propellant filling
  - Development of propellant, igniters, filling and assembling are strongly linked

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## Outlook

- Complete the characterisation of the ignition and combustion in smaller dimensions
- Optimised designs and fabrication processes
  - Nozzles
  - Igniters
  - Assembling
- **Validation of the technology in a space mission**

## MicroPyros

- Project funded by the European Commission
- Involved partners:



ALBERT-LUDWIGS-UNIVERSITÄT FREIBURG



The Angström Applied Technology Centre  
UPPSALA UNIVERSITY